



Additive Manufacturing Circuitry on Rigid and Flexible Substrates for Space Applications

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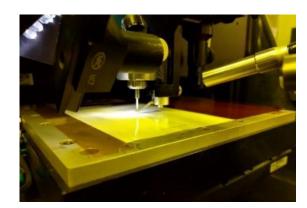


Outline/Agenda

- Introduction: Additive Manufacturing Techniques
- Next Generation X-Ray Polarimeter
- Next Generation Microshutter Array
- **Future Work**
- Acknowledgements
- Q & A

Introduction: Additive Manufacturing Methods Used

Printed Hybrid Electronics: Deposit inks onto substrate



Aerosol Jet

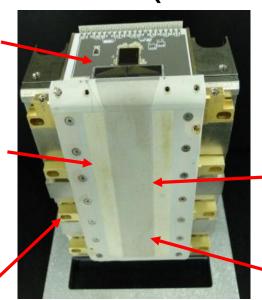
Why?

- Feature sizes down to 10 microns
- Variety of substrates flexible, rigid, 3-dimensional non-planar
- > Has the potential to reduce mass and volume

Next Generation X-Ray Polarimeter (NGXP)

ASIC Board

3 in x 5 in Liquid Crystal Polymer (LCP)



Photoelectron tracks imaged using strip detectors in a gas environment

Fan-out area

Frame

Traces: 121µm pitch, copper cladding etched

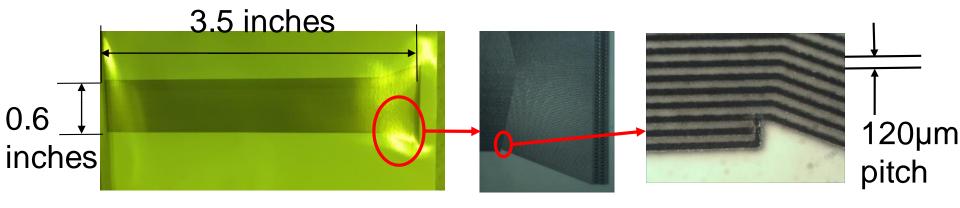
Original Strip Detector

To be presented by Beth Paquette at the SMTA Additive Electronics Conference, San Jose, CA, October 24, 2019



- Materials:
 - □ Gold and silver inks
 - Kapton and Liquid Crystal Polymer (LCP) Substrates
- Printer:
 - □ Optomec AJ200
 - □ Pneumatic atomizer for silver ink
 - □ Ultrasonic atomizer for gold ink

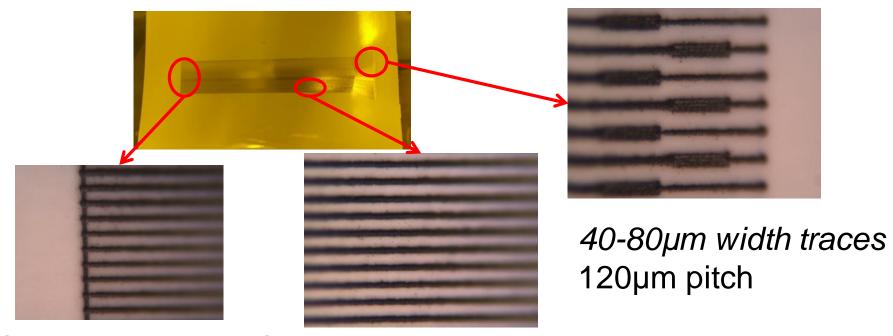
NGXP Flexible Prints



Silver printed on Liquid Crystal Polymer with pneumatic atomizer. 200µm tip used.

Traces 60-80µm throughout print.

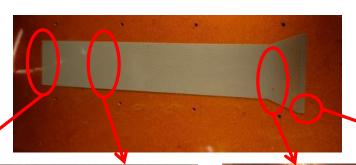
NGXP Flexible Prints



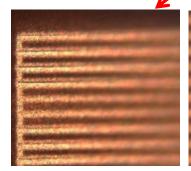
Silver printed on LCP with pneumatic atomizer and 100µm tip

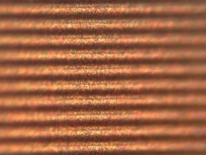
NGXP Flexible Prints

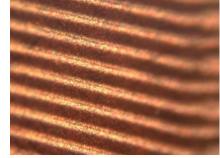
80µm width traces 120µm pitch

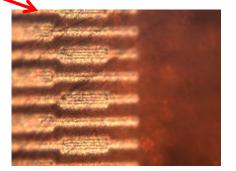


Gold on Kapton Ultrasonic atomizer 200µm tip









Ink appeared dry and powdery. Overspray observed

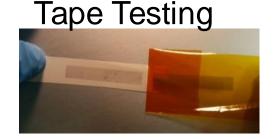
NGXP Flex Mechanical Tests



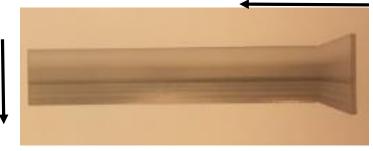
Bend Testing



Tensile Testing



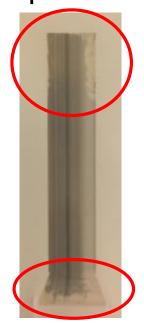
Pull directions

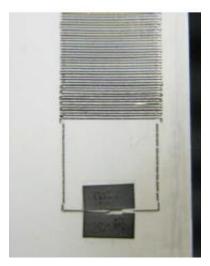


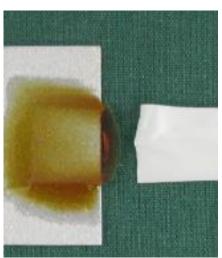
NGXP Flex Mechanical Tests

Tape Tests







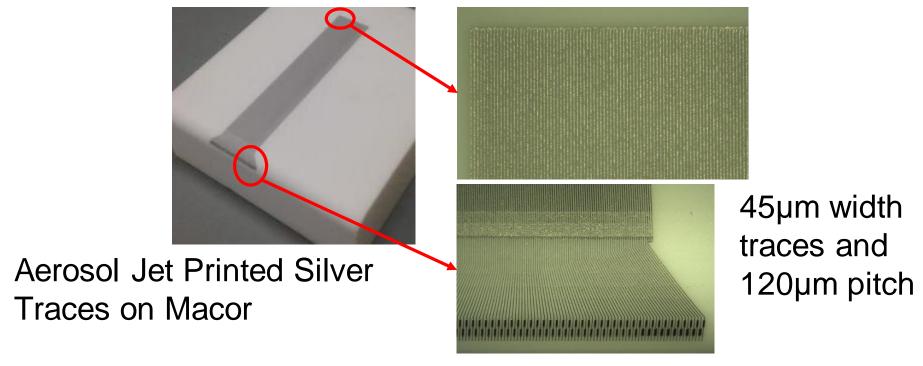


Trace, bond and LCP breaks observed

NGXP Flex Observations

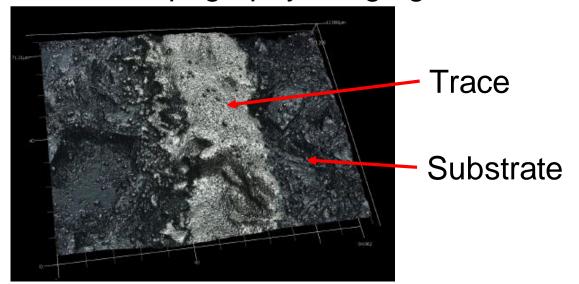
- Printing parameters need to be adjusted over length of print
- Results vary between printer operators
- Gold ink more cumbersome to use, store
- Adhesion of inks to LCP needs improvement

NGXP Rigid Prints



NGXP Rigid Print Tests

Visual and topography imaging



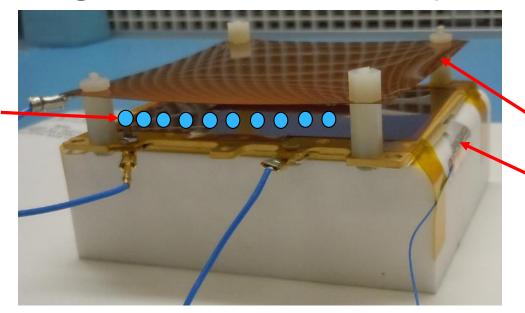
Traces measured 45.5µm+/-4.4µm



ASTM Adhesion Class 5B and 4B observed

NGXP Rigid Print X-Ray Tests

X-Rays move perpendicular to traces



Electrode layer Printed Strip

Strip survived 16 hours of X-Ray testing

NGXP Rigid Print Observations

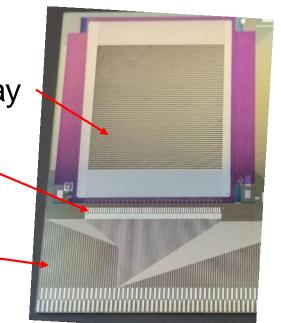
- Prints on rigid substrates yielded ASTM Class 4B and 5B adhesion (minimal material removed)
- Substrate topography may impact trace structure and conductivity
- Prints survived X-Ray chamber

Next Generation Microshutter Arrays (MSA)

Microshutter Array

128 pairs of metal pads

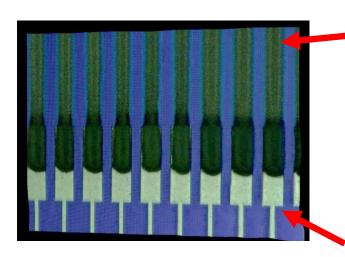
Silicon Substrate



High-resolution spectroscopy:

Microshutters select many objects in one viewing for simultaneous observation

MSA Aerosol Jet (AJ) Test Prints Printed

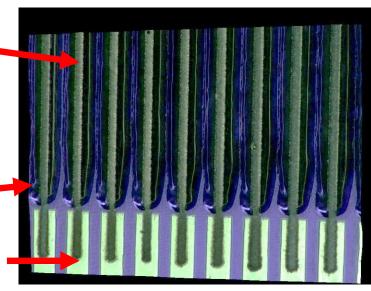


Printed Silver Lines

Printed Insulator

Metal Pads

Sample without insulator



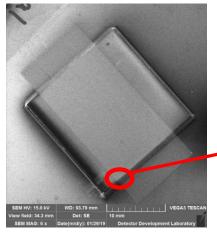
Sample with insulator

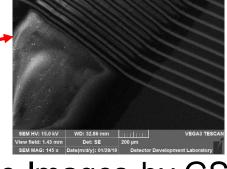
Conductivity tests were successful

MSA AJ Test Prints

Printed Sample on Silicon

Printed silver lines with 20um Squares attached to Wafer width over insulating fillet/"ramp"





Scanning Electron Microscope Images by GSFC

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MSA AJ Test Prints

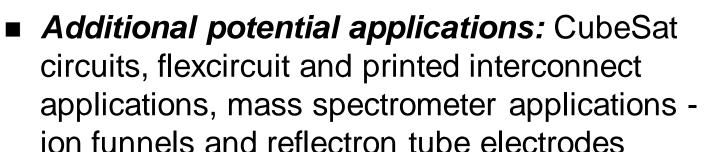


Probe setup (Optomec)

- Resistance measured across conductive traces: 12Ω
- Between traces:
 - Resistance on order of $M\Omega$, but needs to be on order of $G\Omega$
 - Trying plasma treatment to increase resistance
 - Printing a second set of interconnects on a new wafer

Future Work

- Work with syringe printer
- Continue Testing
- Integrate ASIC board design into NGXP





Syringe Print 3D Flexible, Inc

Acknowledgements

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- Justin Bourassa, Mike Renn, Optomec
- Victor Yun, 3D Flexible Inc







Thank You!

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| Acronym | Definition |
|---------|---|
| AJ | Aerosol Jet |
| ASIC | Application Specific Integrated Circuit |
| ASTM | American Society of Testing and Materials |
| LCP | Liquid Crystal Polymer |
| MSA | Microshutter Array |
| NGXP | Next Generation X-Ray Polarimeter |
| PEEK | Polyetheretherketone |

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